PROPOSED AMENDMENTS TO INDEPENDENT CLAIMS

Serial No.: 09/595,583; Docket No.: 30-5074(4015)

1. A method of generating information about particulates present in a fluid <u>utilizing a microscope</u>, comprising:

providing a substrate having comprising a first shade:

filtering the fluid through the substrate, the particulates being retained on the substrate during the filtering, the filtering imparting a second shade to at least a fraction of the substrate:

after the filtering, scanning across at least a portion of the substrate with a microscope, the scanning comprising automated displacement of the substrate relative to an observing portion of the microscope along a pattern, the microscope obtaining data about said particulates at locations along the pattern;

digital image processing of the data obtained by the microscope to generate information about said particulates; and

determining a contrast of two or more of the particulates relative to the fraction of the substrate comprising the second shade.

9. A method of generating information about materials present in a composition <u>utilizing a microscope</u>, comprising:

providing a composition having a purity of at least 99.995%;

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utilizing a reagent to dissolve at least a portion of the composition and thereby form a mixture;

filtering the mixture through a substrate, at least some components of the mixture being retained on the substrate during the filtering;

after the filtering, scanning across at least a portion of the substrate with a microscope to obtain one or more images of the substrate; and

digital image processing of the one or more images to generate information about said retained components, at least some of the generated information relating to a relative contrast of the components.

A method of generating information about materials present in a 14. composition utilizing a microscope, comprising:

utilizing a reagent to disperse a first portion of the composition and thereby form a first solution comprising a dispersion of undissolved material;

filtering the first solution through a first substrate, at least some of the undissolved material being retained on the first substrate during the filtering;

forming a second solution comprising a dispersion of undisolved material from a second portion of the composition;

filtering the second solution through a second substrate, at least some undissolved material being retained on the second substrate;

scanning across at least a portion of the first substrate with a microscope, the scanning comprising automated displacement of the first substrate relative to an observing portion of the microscope along a grid pattern, the microscope obtaining <u>a first set of</u> data about said retained undissolved material at locations along the grid pattern, at least some of the obtained <u>first set of</u> data relating to a relative contrast of the retained undissolved material:

scanning across at least a portion of the second substrate with a microscope, the scanning comprising automated displacement of the second substrate relative to an observing portion of the microscope along a grid pattern, the microscope obtaining a second set of data about said retained undissolved material at locations along the grid pattern, at least some of the obtained second set of data relating to a relative contrast of the retained undissolved material;

processing the <u>first set of data and the second set of data obtained</u> by the microscope to generate information about one or more of the size, shape, type and quantity of undissolved material, undissolved material type being related to at least one of a conductivity, an oxide content and a carbon content of the undissolved material; and

depth profiling the composition, the depth profiling comprising comparing information generated from the first substrate set of data to information generated from the second set of data substrate.

35. A method of generating information about materials present in a composition <u>utilizing a microscope</u>, comprising:

providing a composition comprising at least one of Sb, Pb and Sn;

selectively dissolving some components of the composition in a reagent while leaving other components undissolved;

collecting at least some of the undissolved components on a filter surface;

scanning across at least a portion of the filter surface with a light microscope, the scanning comprising automated displacement of the filter surface relative to an observing portion of the microscope along a grid pattern, the microscope obtaining data about scattering of light by the undissolved components on the filter surface, the undissolved components comprising at least two types, a first of the two types being darker than a background defined by the filter surface and a second of the two types being lighter than the background; and

digital image processing of the data obtained by the microscope to generate information about one or more of the size, quantity and aspect ratio of the undissolved components; the processing comprising a sort of the undissolved components amongst the two types.

40. A method of generating information about impurities present in a metal composition <u>utilizing a microscope</u>, comprising:

utilizing a reagent to selectively dissolve a portion of the composition relative to at least some impurities present in the metal composition, the dissolved portion forming a solution with the reagent; the impurities being at least two different types; on of the at least two types being a first type comprising a

first material, and another of the at least two types being a second type comprising a second material, the second material differing from the first material;

filtering the solution through a substrate, at some of the first and second types of the impurities being retained on the substrate during the filtering;

after the filtering, modifying a light absorbing property of at least some of the impurities retained on the substrate;

scanning across at least a portion of the substrate with a light microscope, the scanning comprising automated displacement of the substrate relative to an observing portion of the microscope along a grid pattern, the microscope obtaining data about the impurities at locations along the grid pattern, the data including a relative darkness of the impurities relative to a background defined by the substrate; the first type of impurities being darker than the background and the second type of impurities being lighter than the background; and

processing the data obtained by the microscope to generate information about the size, quantity and type of the impurities.